Cure-Kinetics Modeling and Process Optimization for Next-Generation Interlayer Dielectrics - II

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OBJECTIVE

□ To conduct comprehensive thermal and mechanical characterization of the photo-dielectric-dry-film (PDDF) material. This includes:

□ development of a cure-kinetics model to aid in the understanding and optimization of the curing schedule, as well as to understand structure-property relationships

□ mechanical characterization of partially and fully cured material

□ Fabrication of high-density features (lines, microvias, etc.) with reduced thermal bake times

□ Note: the characterization information will be input into the integrated cure-thermal-stress analysis module, which is being developed concurrently to predict the evolution of stresses and warpage during SOP substrate fabrication

ACCOMPLISHMENTS

□ Understood the complex 2-peak cure mechanism of the PDDF (attributed to the long lifetime of the cationic photoinitiator catalyst), and developed cure-kinetics model's based on both multiple heating rate and isothermal DSC experiments

□ Selected an increased exposure dose of 2000 mJ/cm², which caused a significant reduction in the post-exposure bake time, as well the final thermal bake time

□ Demonstrated the fabrication of microvias, as well as other complex features using the optimized cure processing schedule

□ Completed the mechanical characterization of the PDDF, which included determination of the CTE and bulk modulus of the fully cured material, and the cure-dependent viscoelastic stress relaxation modulus

□ Papers published in J. of App. Polymer Science, IEEE Trans., ECTC, and IMAPS conferences

APPROACH

□ Study the effect of UV exposure on the rate of curing, and select a suitable value to reduce cure processing times

□ Use multiple heating rate as well as isothermal DSC experiments to develop a phenomenological cure kinetics model. Two modeling approaches were implemented to predict the evolution of DOC:

□ based on dynamic DSC data, using a model-free method involving the cure-dependence of the activation energy

□ based on isothermal DSC data, using a modified auto-catalytic model with temperature-dependent kinetic parameters

□ To optimize the microvia fabrication process, the post-exposure bake time at 110 °C is reduced using a trial-and-error experimental approach, while the final thermal bake time is reduced using the cure kinetics model

Determine the CTE, bulk modulus and cure-dependent stress relaxation modulus using the TMA, PVT dilatometer and DMA respectively



Subsequent DSC scan data at 10 °C/min of samples cured isothermally at the temperatures shown in the legend box (Exposure dose = 2000 mJ/cm^2



Representative microvias



Representative lines and features